

Reg No.: _____

Name: _____

APJ ABDUL KALAM TECHNOLOGICAL UNIVERSITY
Seventh Semester B.Tech Degree Supplementary Examination August 2021

Course Code: EC465

Course Name: MEMS

Max. Marks: 100

Duration: 3 Hours

PART A

Answer any two full questions, each carries 15 marks.

Marks

- 1 a) Describe the working principle of pressure sensor with neat sketches. (7)
- b) Explain the operation of thermal sensors and actuators with neat diagrams. (8)
- 2 a) Describe the working principle of micro accelerometer with neat schematic diagrams. (7)
- b) Discuss the working principle of electro static sensors and actuators. (8)
- 3 a) Explain the operating principle of two types of micro motors with suitable schematics. (8)
- b) Evaluate different types of flexural beams and boundary conditions that are encountered in MEMS. (7)

PART B

Answer any two full questions, each carries 15 marks.

- 4 a) Explain Trimmer Force Scaling Vector. Analyze the scaling equations for Acceleration, time and Power Density in terms of force scaling vector. (8)
- b) Explain the steps involved in photolithography. State the chemicals used in each Stage. (7)
- 5 a) Analyze the expressions for electromagnetic potential energy and force with reference to scaling of electromagnetic forces. (7)
- b) Discuss the properties of PDMS and PMMA with neat diagrams. (8)
- 6 a) Explain the scaling in fluid mechanics .What are the advantages of piezoelectric pumping. (8)
- b) Explain the working principle Chemical Vapor Deposition used for obtaining Silicon Nitride thin film over silicon substrate. (7)

PART C

Answer any two full questions, each carries 20 marks.

- 7 a) Explain surface micro machining process with neat sketches. (10)
b) Differentiate between Anodic bonding and Silicon Fusion Bonding. (10)
- 8 a) Describe the process of Micro stereo lithography with neat sketches. (10)
b) Explain with figures two applications which use RF MEMS technology. (10)
- 9 a) Explain the general considerations in packaging of MEMS system design. (10)
b) Explain the different stages in Sealing of micro systems. (10)
